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10/3/03*H/C Amdt*

Customer No.: 31561
 Application No.: 10/064,208
 Docket No.: 8309-US-PA

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re Application of:)	
CHEN)	Examiner : Christopher G.
)	Young
Serial No. : 10/064,208)	Art Unit : 1756
Filed : 06/21/2002)	Docket No. : 8309-US-PA
For : SUBSTRATE EXPOSURE)	
APPARATUS AND METHOD)	

No fee is believed to be due. However, the Commissioner is authorized to charge any fees required in connection with the filing of this paper to account No. 50-2620 (Order No. 8309-US-PA).

AMENDMENTS AND RESPONSE TO OFFICE ACTION

U.S. Patent and Trademark Office
 Commissioner for Patents
 2011 South Clark Place
Customer Window, Mail Stop Non-Fee Amendment
 Crystal Plaza Two, Lobby, Room 1B03
 Arlington, Virginia 22202

Dear Sir:

In reply to the Office Action dated June 26, 2003, Applicants submit the following Amendments and Remarks.

10/06/2003 CSIAS1 00000006 502620
 01 FC:1202 198.00 DA

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AMENDMENTS

Please amend the application as indicated hereafter.

In the Claims:

1 (withdrawn). A substrate exposure apparatus, applicable to transfer a pattern to a photoresist on a surface of a substrate, the substrate exposure apparatus comprising:

a scan light source, disposed at a position spaced from a surface of the photoresist on the substrate with a distance, and the scan light source comprising a plurality of point light sources; and

a scan control system, converting the pattern into a timing signal to control light and dark status of each of the point light sources at different times, the scan control system further allows the substrate exposure apparatus to have a scan function, such that the scan light source scans the photoresist at least once along a scan path for exposure.

2 (withdrawn). The substrate exposure apparatus according to claim 1, wherein the substrate includes a printed circuit board.

3 (withdrawn). The substrate exposure apparatus according to claim 1, wherein the substrate includes a wafer.

4 (withdrawn). The substrate exposure apparatus according to claim 1, wherein the substrate includes various types of package substrates.

5 (withdrawn). The substrate exposure apparatus according to claim 1, wherein the point light sources are arranged into one line light source.